



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Application Serial No. 09/536,037
Filing Date March 27, 2000
Inventor Weimin (Michael) Li et al.
Assignee Micron Technology, Inc.
Group Art Unit 2822
Examiner Toniae M. Thomas
Attorney's Docket No. MI22-1398
Title: Low k Interlevel Dielectric Layer Fabrication Methods

SUPPLEMENTAL INFORMATION DISCLOSURE STATEMENT

References -- See attached Form PTO-1449

In compliance with 37 C.F.R. §§ 1.56, 1.97 and 1.98, your attention is directed to the United States patents and other references listed on the attached Form PTO-1449. No admission is made regarding whether all the submitted references are prior art.

This Supplemental Information Disclosure Statement is being filed together with the filing of the Request for Continued Examination (RCE) Application and before receipt of the first Office Action. Therefore, no fee is believed to be required. However, in the event that a fee is required for filing this Supplemental Information Disclosure Statement, please charge the fee specified under 37 C.F.R. §1.17(p) to Deposit Account No. 23-0925.

Please credit Deposit Account No. 23-0925 with any overpayment of the above fee.

Citation of these references is respectfully requested.

Respectfully submitted,

Date: 09 Oct 2003


James E. Lake
Reg. No. 44,854

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U.S. DEPARTMENT OF COMMERCE
PATENT AND TRADEMARK OFFICEATTY. DOCKET NO.
MI22-1398SERIAL NO.
09/536,037APPLICANT
Weimin (Michael) Li et al.FILING DATE
March 27, 2000GROUP
2822LIST OF ART CITED BY APPLICANT
(Use several sheets if necessary)

U.S. PATENT DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	6,518,122	02/03	Chan et al.			
	AB	6,492,688	12/02	Ilg (ILG)			
	AC	6,373,114	04/02	Jeng et al.			
	AD	6,001,747	12/14/1999	Annapragada			
	AE	2001/0019868	9/01	Gonzalez et al.			
	AF	2001/0003064	601	Ohto			
	AG	2003/0013311	1/03	Chang et al.			
	AH						
	AI						
	AJ						
	AK						
	AL						

FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AR		"Silicon Processing for The VLSI Era"; Wolf, Stanley, Ph.D., Lattice Press 1986					
	AS							
	AT							

EXAMINER

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*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.